



T-I Max

Next-Generation AMC Monitors

GASES & CHEMICALS

CEMS

ENERGY

SEMI & HB LED

ATMOSPHERIC

LAB & LIFE SCIENCE

Based on Tiger Optics' new global platform, the T-I Max series monitors for Airborne Molecular Contaminants (AMCs) deliver unprecedented performance, including:

- Sensitive, absolute measurement technique, using Cavity Ring-Down Spectroscopy (CRDS)
- Dramatically improved speed of response
- Parts-per-trillion detection limits
- Drift-free, with calibration traceable to the world's leading reference labs
- Lowest Cost of Ownership and maintenance

Next-Generation Trace Gas Analyzers for Detection & Continuous Monitoring of Airborne Molecular Contaminants in Semiconductor Cleanrooms

You can spend a long time “looking” for Airborne Molecular Contaminants (AMCs) when the catastrophic product performance or yield loss is discovered at your device final test stage; or you can deploy Tiger Optics' T-I Max series analyzers to locate and to monitor these invisible defect generators, commonly found lurking in and around equipment, personnel, wafer carriers and cleanroom bays.

In today's advanced semiconductor processing, the residual gases, vapors and chemicals emanating from the various materials, accelerated processing operations, and substrate storage and transport have become a critical concern. So much so that the International Technology Roadmap for

for Semiconductors (ITRS) now highlights AMC contamination as a key technical challenge in achieving & sustaining low defect rates on devices.

With a particular focus on the major contributors to the “chemical contamination” element of AMCs, the T-I Max series, based on Tiger's new analyzer platform, can detect and continuously monitor HF, HCl, and NH₃ with an unprecedented combination of sensitivity, selectivity, and speed of response.

Tiger Optics' GO-cart for AMCs adds additional flexibility by providing a mobile platform that can be moved quickly to different critical monitoring points.

T-I Max

Next-Generation AMC Monitors



Performance		Dimensions	H x W x D [in (mm)]
Operating range	See table below	Standard sensor	8.73 x 8.57 x 23.6 (222 x 218 x 599)
Detection limit (LDL, 3σ@100s)	See table below	(w/o ext. particle filter)	
Precision (1σ@100s, greater of)	± 0.5% or 1/3 of LDL	Sensor rack	8.73 x 19.0 x 23.6 (222 x 483 x 599)
Accuracy at span	± 4% of reading	(fits up to two sensors)	
Accuracy at zero	See table below	GO-cart	50 x 23 x 36 (1270 x 584 x 914)
Speed of response @ 20ppb	See table below		
(T10/90 + T90/10)			
Environmental conditions	10°C to 40°C	Weight	
	10% to 90% RH (non-condensing)	Standard sensor	33 lbs (15 kg)
Sample conditions	30% to 70% RH at 20°C	GO-cart	260 lbs (118 kg)
	20% to 50% RH at 25°C	(both excl. vacuum pump)	
	15% to 40% RH at 30°C		
Storage temperature	-10°C to 50°C	Electrical and Interfaces	
		Platform	Max series analyzer
		Alarm indicators	2 user programmable
			1 system fault
			Form C relays
		Power requirements	90 – 240 VAC, 50/60 Hz
		Power consumption	40 Watts max.
		Signal output	Isolated 4–20 mA
		User interfaces	5.7" LCD touchscreen
			10/100 Base-T Ethernet
			USB, RS-232, RS-485
			Modbus TCP (optional)
		Data storage	Internal or external flash drive
		Certification	CE Mark
Gas Handling System and Conditions*			
Wetted materials	Optimized for ppt-level AMCs and fast speed of response		
Gas connections	1/4" PFA Swagelok® inlet & outlet		
Inlet pressure	Atmospheric pressure†		
Outlet pressure	Vacuum (<10 Torr)		
Flow rate	-3 slpm@1 atm pressure (NH ₃)		
	-2 slpm@1 atm pressure (HF, HCl)		
Sample gases	Cleanroom air, CDA or N ₂		
Gas temperature	Up to 60°C		

Performance in cleanroom air:	Range	LDL (3σ@100s)	Accuracy at zero	Speed of Response (T10/90+T90/10)
T-I Max HF	0 – 1 ppm	20 ppt	± 20 ppt	< 3 minutes @ 20 ppb
T-I Max HCl	0 – 4 ppm	100 ppt	± 100 ppt	< 30 seconds @ 20 ppb
T-I Max NH ₃	0 – 40 ppm	300 ppt	± 300 ppt	< 3 minutes @ 20 ppb

*Vacuum source with >2 slpm @ 10 Torr required

†Contact us for details about operating the analyzer at elevated inlet pressure.

Contact us for additional analytes.

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